



#1 CoA  
2877  
M. Brunson  
4/30/01

EX-100  
EX-12  
10 2600 MAIL ROOM

XA-9387  
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Hitoshi TAKEUCHI

Group Art Unit: 2877

Appln. No.: 09/714,183

Filed: November 17, 2000

For: ABERRATION MEASURING APPARATUS, ABERRATION MEASURING  
METHOD, PROJECTION EXPOSURE APPARATUS HAVING THE  
SAME MEASURING APPARATUS, DEVICE MANUFACTURING  
METHOD USING THE SAME MEASURING METHOD, AND EXPOSURE

CHANGE OF CORRESPONDENCE ADDRESS

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

Effective immediately, please address all further  
correspondence in the above-identified application to:

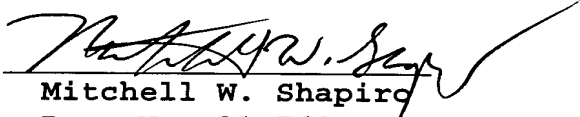
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(703) 903-9000.

Respectfully submitted,

MWS:pdh

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(703) 610-8652

By:

  
Mitchell W. Shapiro  
Reg. No. 31,568

April 11, 2001